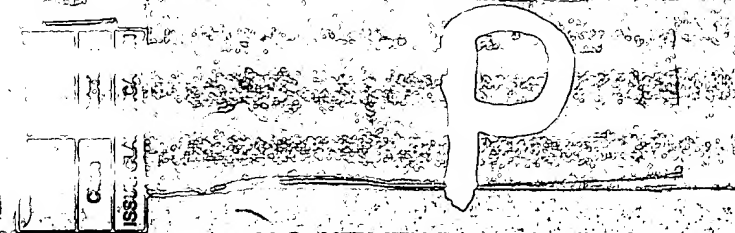


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U.S. UTILITY Patent Application

OL/P

PATENT DATE

1.6.3.1

APPLICATION NO.	CONT/PRIOR	CLASS	SUBCLASS	ART UNIT	EXAMINER
09/880584	D	438	715	1762 183	644/dga Zervig

APPLICANTS

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TITLE

Method for minimizing the critical dimension growth of a feature on a semiconductor wafer

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